

A New Facility for Secondary Electron Measurement

The secondary electron is researched in many field. In order to measurement the secondary electron angular distribution of all the solid angle, the X axis support, Y axis support is promoted. The spectral distribution of the secondary electron also can be measured. The accumulataion charge on the insulated material surface during the secondary electron measurement have very bad effects. Although many methods have been used for the charge neutralization, many defects are still not resolved. So the plasma neutralization is promoted. The plasma neutralization can also be used in the electron microscopy.

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